

Optical Plasma Diagnostics in High Intensity Electron Beam Diodes

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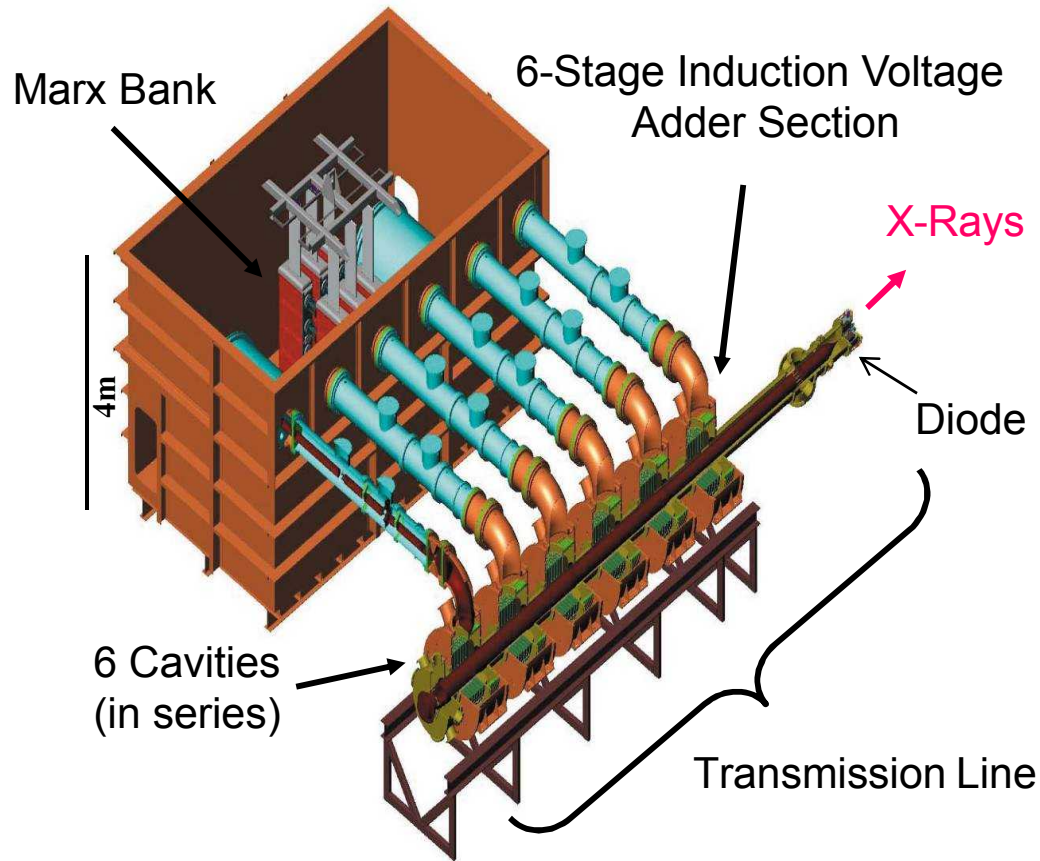
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Outline

- **RITS-6 Accelerator.**
- **Negative Polarity Rod Pinch (NPRP) Diode.**
- **Self-Magnetic Pinch (SMP) Diode.**
- **Optical Diagnostics Layout on RITS.**
- **PI-Max ICCD Single Frame Fast Imaging System**
- **Optical Streak Imaging System**
- **Avalanche Photodiodes**
- **Plasma Spectroscopy Diagnostic**
- **Plasma Parameters Inferred from Spectral Analyses**
- **Electric and Magnetic Field Measurements**
- **Summary**

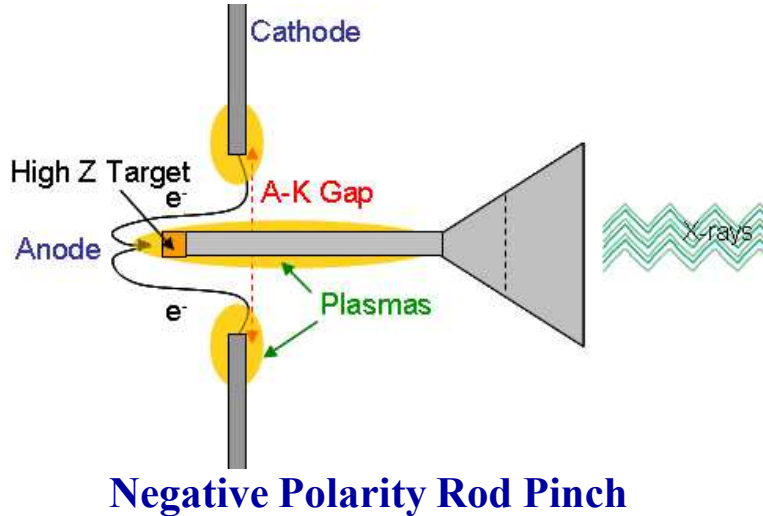
RITS-6 Accelerator at Sandia National Laboratories



RITS-6 is a multi-MeV Marx driven six-stage Inductive Voltage Adder (IVA) machine, capable of driving a variety of electron beam diodes¹.

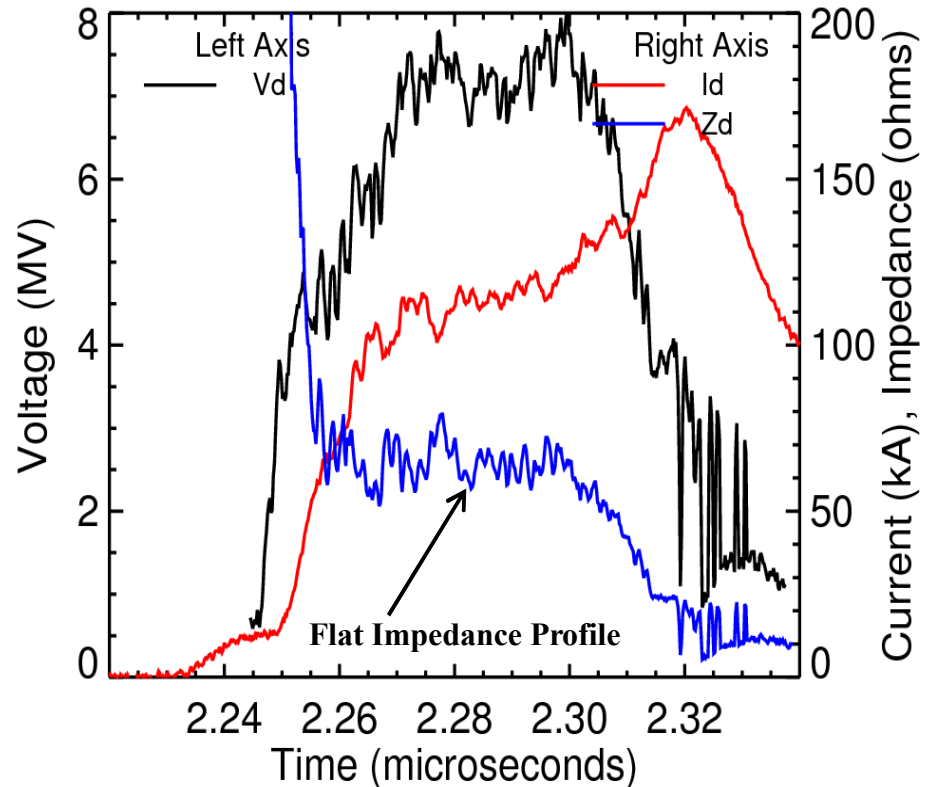
¹D. Johnson, et al., *Proc. 15th IEEE Int. Pulsed Power Conf* (IEEE, Jun. 13-17, 2005) pp. 314–317.

Negative Polarity Rod Pinch (NPRP) Diode Electrical Characteristics

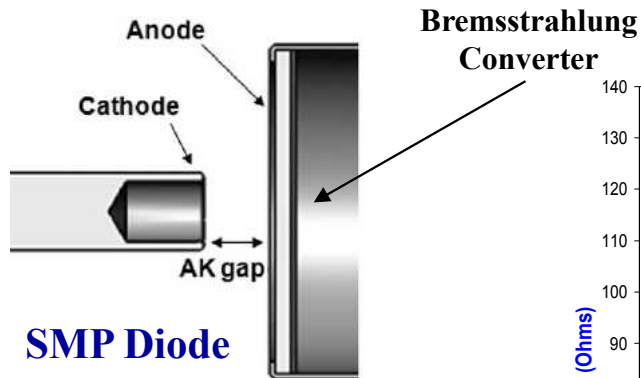


NPRP Diode Parameters

- 6-7 MV
- 120 kA
- 70ns Electrical Pulse
- 50ns Radiation Pulse
- > 120 Rads @ 1 meter
- < 2.6 mm spot size

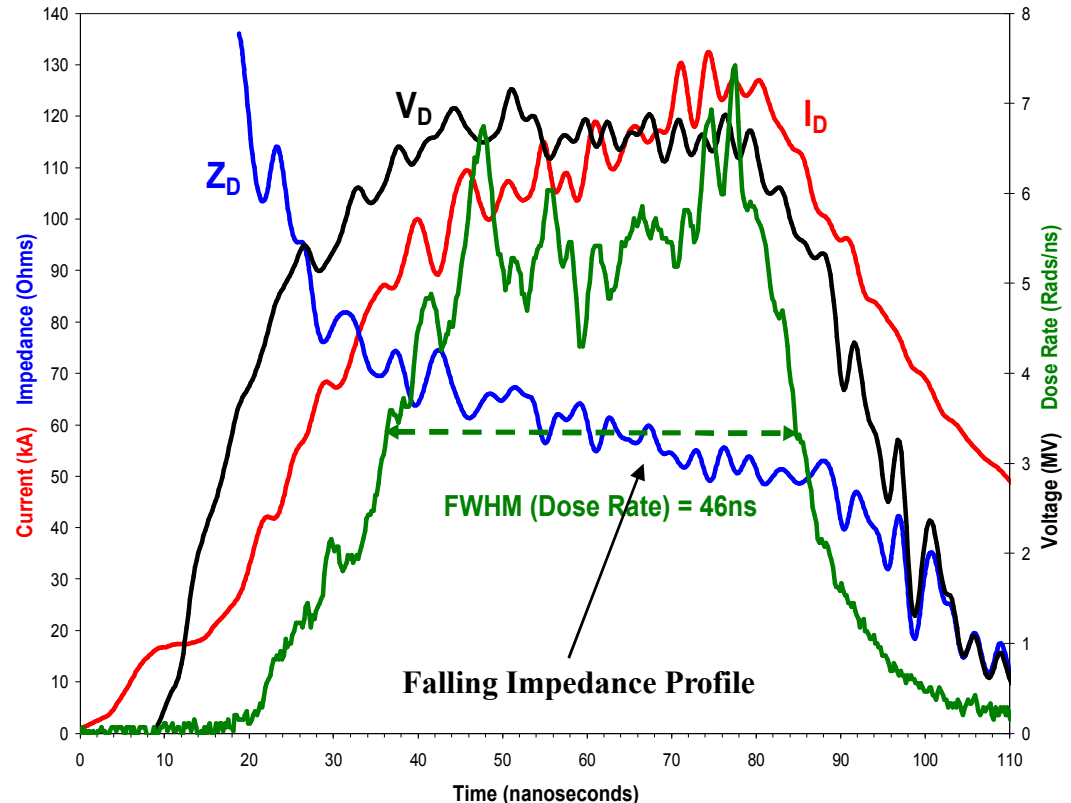


Self-Magnetic Pinch (SMP) Diode Electrical Characteristics



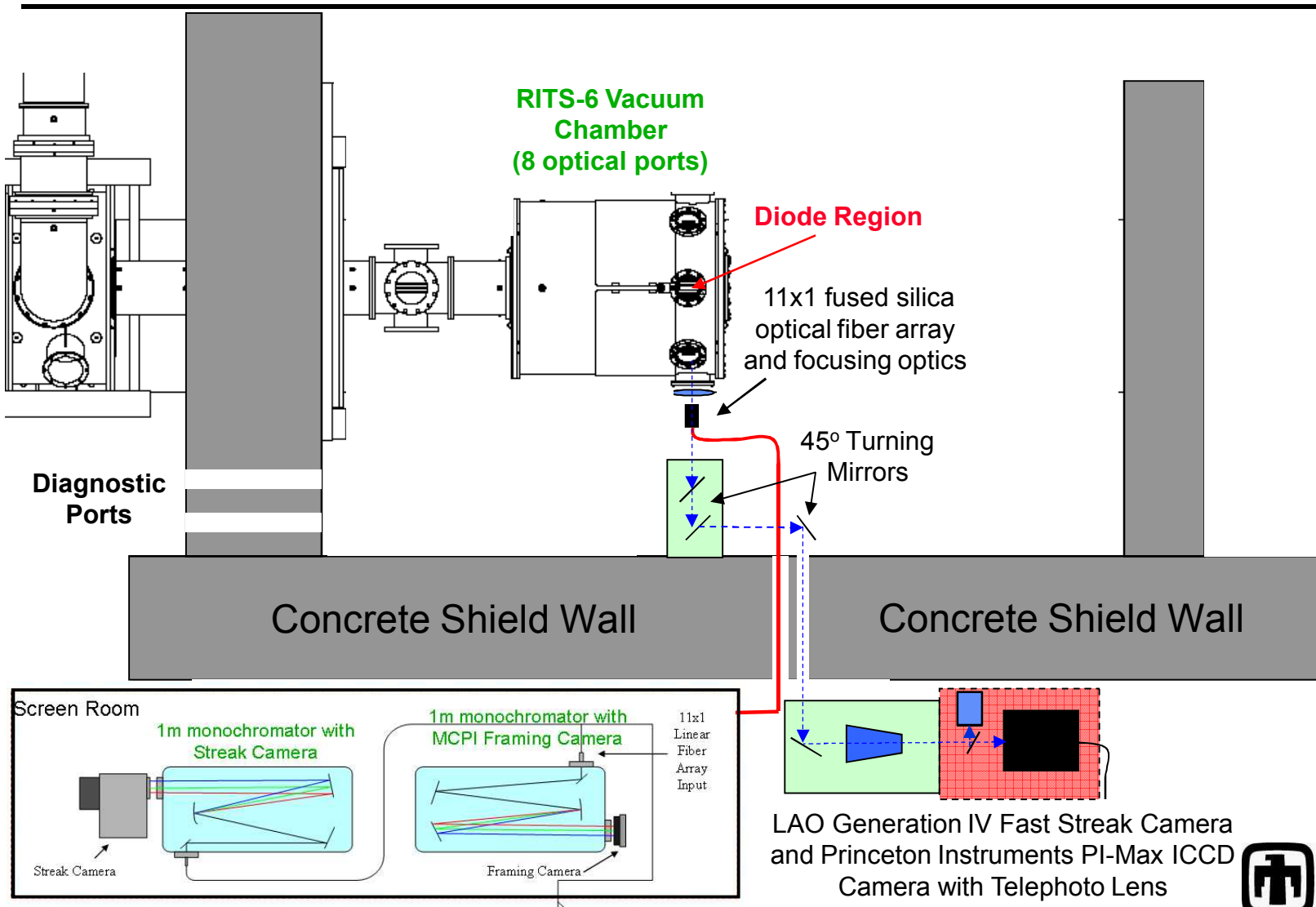
SMP Diode Parameters

- 4-7.5 MV
- 80-150 kA (~15% ions)
- 50 Ω Impedance
- 70ns Electrical Pulse
- 45ns Radiation Pulse
- 90-350 Rads @ 1 meter
- ≤ 2.7 mm focal spot size



**MA/cm² current densities
at the anode!**

Optical Diagnostics Layout on the RITS-6 Accelerator



PI-Max ICCD Single Frame Imaging System

The ICCD Framing camera is a commercially available Princeton Instruments model PI-Max.

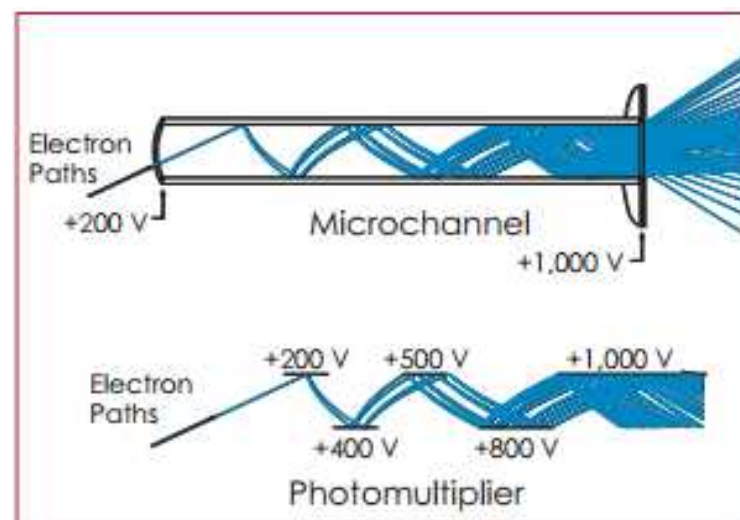
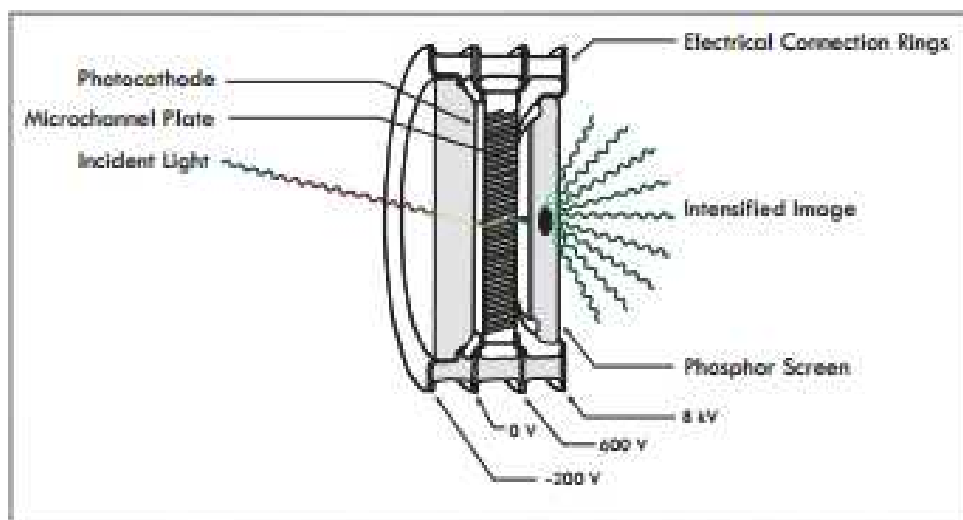
Princeton Instruments PI-Max ICCD Camera

- Gen III filmless GaAsP photocathode (HBf)
- 25mm fiber-optic bonded 1:1 image intensifier
- P43 phosphor screen
- Front-Illuminated CCD
- 1340x1300 pixel array
- 20 micron pixel size
- < 7ns gating
- > 50% peak QE



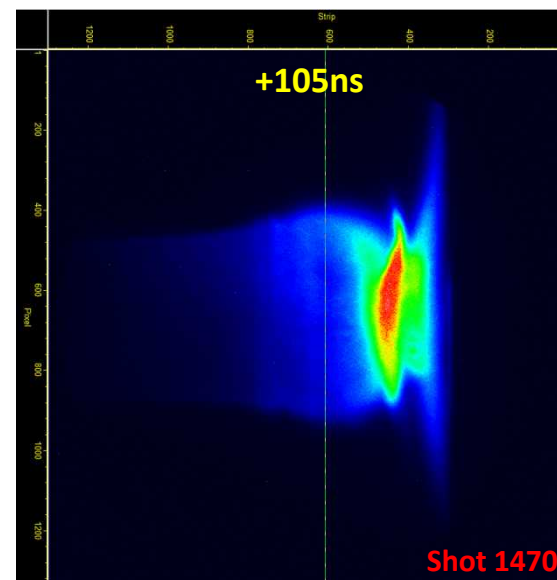
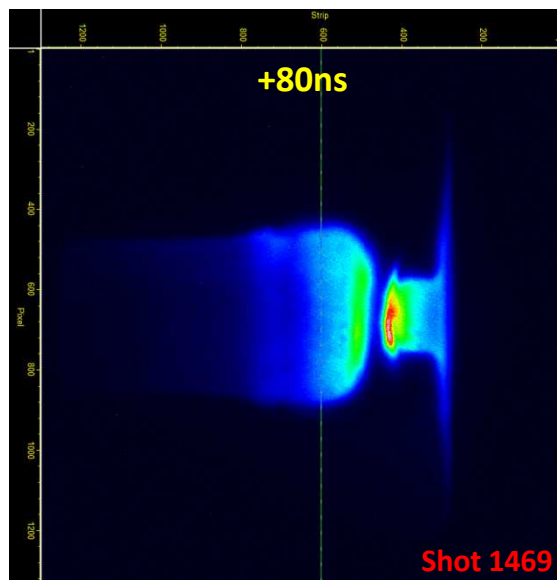
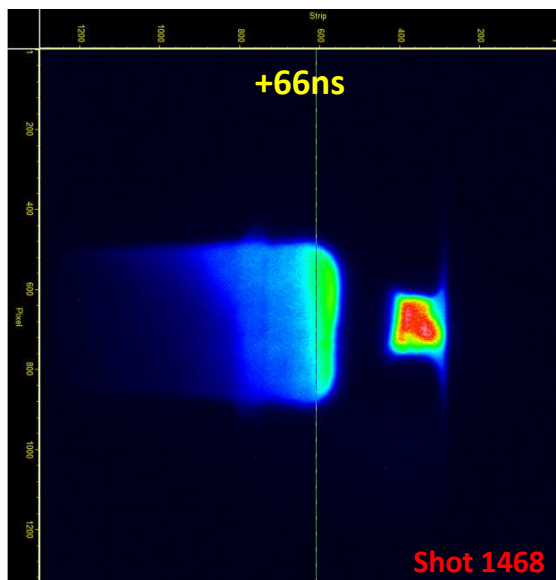
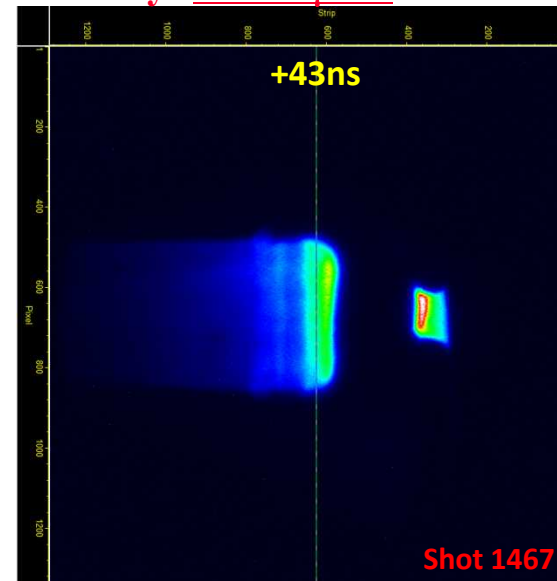
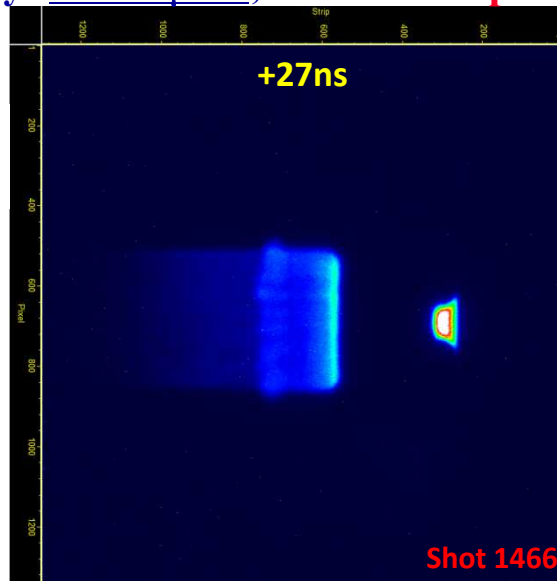
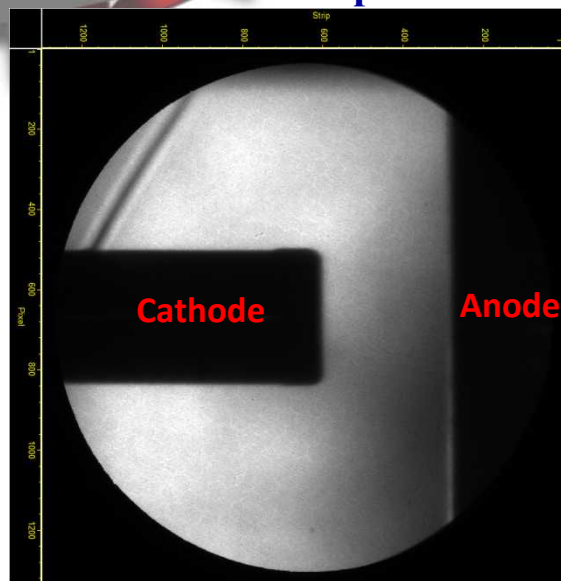
Princeton Instruments
PI-Max Camera

(A) Microchannel Plate,
(B) Fiber-optic faceplate, and (C) CCD



Framing Camera Images of Electrode Plasma Expansion

Anode Expansion Velocity: $3.5\text{cm}/\mu\text{sec}$; Cathode Expansion Velocity: $1.7\text{cm}/\mu\text{sec}$



*Green line represents original cathode position

*10ns images

Optical Streak Camera Plasma Imaging Diagnostic

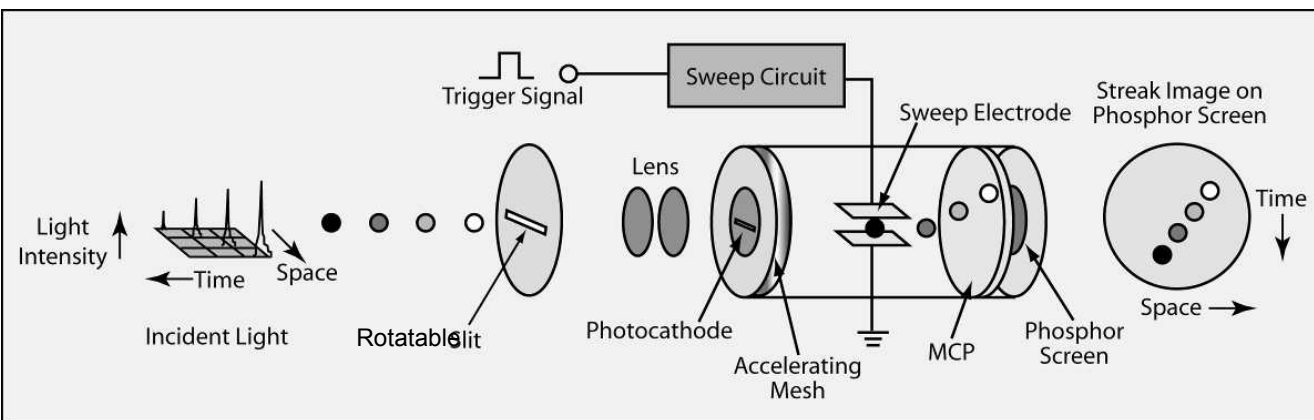
The optical streak imaging system was designed around the NSTec Gen IV Streak Camera.

NSTec Gen IV Streak Camera

- Continuously Selectable Sweep Rates from 20ns to 500 μ s
- Photonis P510 Streak Tube
- 6 μ m Fiber Faceplate (Input/Output)
- 35mm x 4mm Active Area Multi-alkali S-20 Photocathode
- 60mm Aluminized P-22 Phosphor Screen
- Selectable/rotatable input slit sizes
- Full remote control capability from external work station

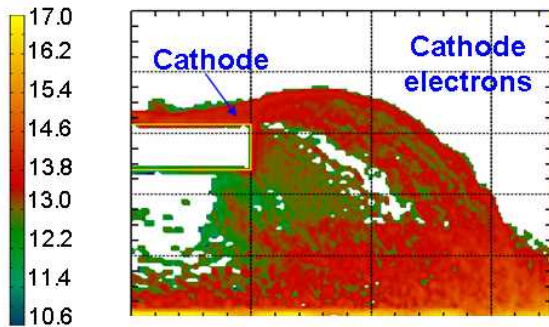
Princeton Instruments Quad-Ro CCD

- 24 μ m pixels
- 50mm chip

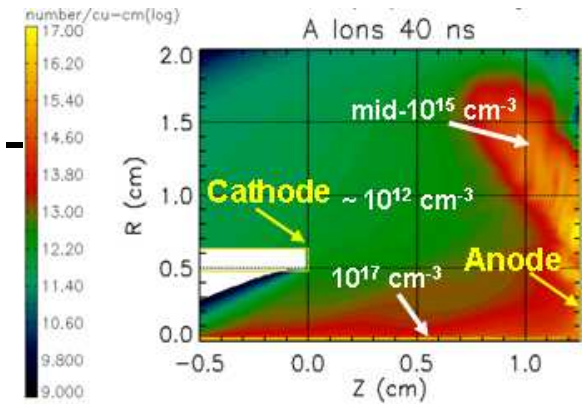
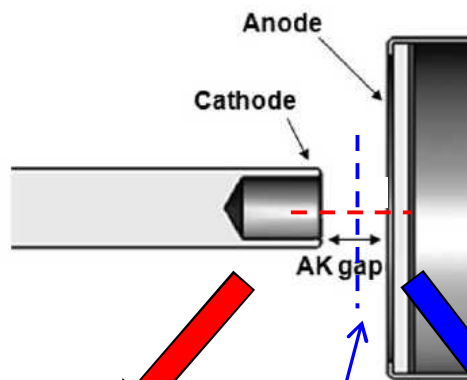


Princeton Instruments Quad-Ro CCD
(Streak camera detector)

Typical Streaked Images of A-K Gap Plasmas

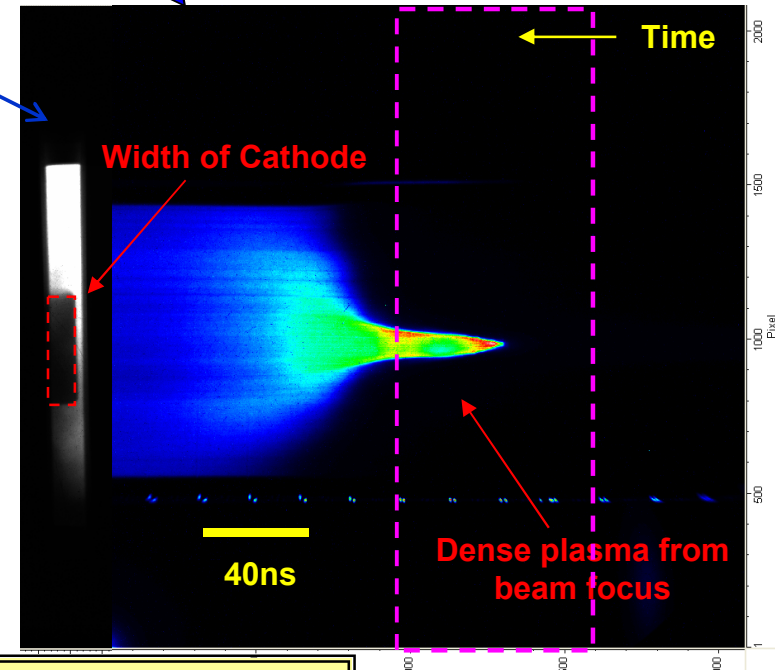
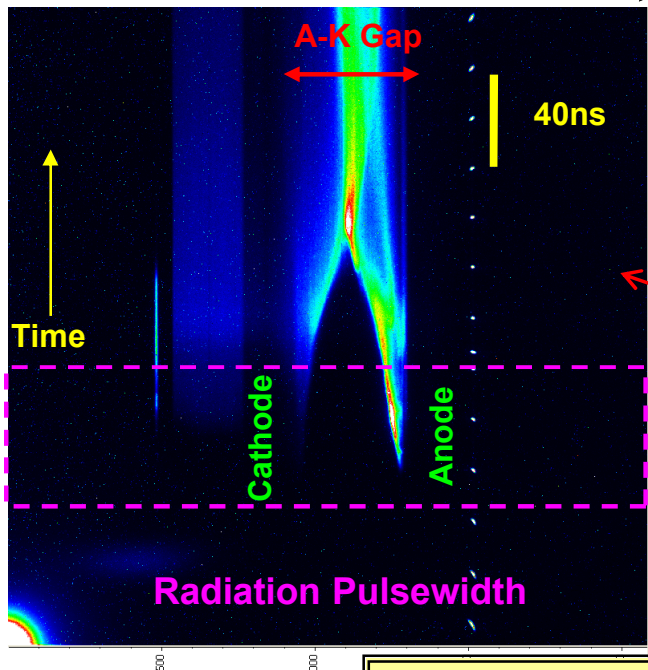


Hybrid particle-in-cell (PIC)/fluid simulations using LSP code



Radial Plasma Evolution

Axial Plasma Evolution



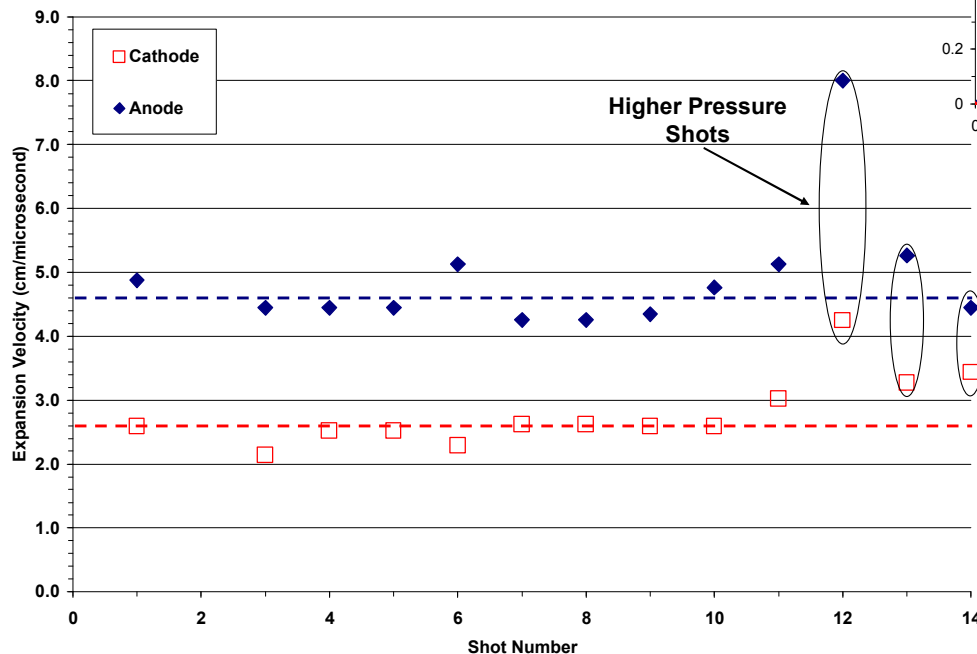
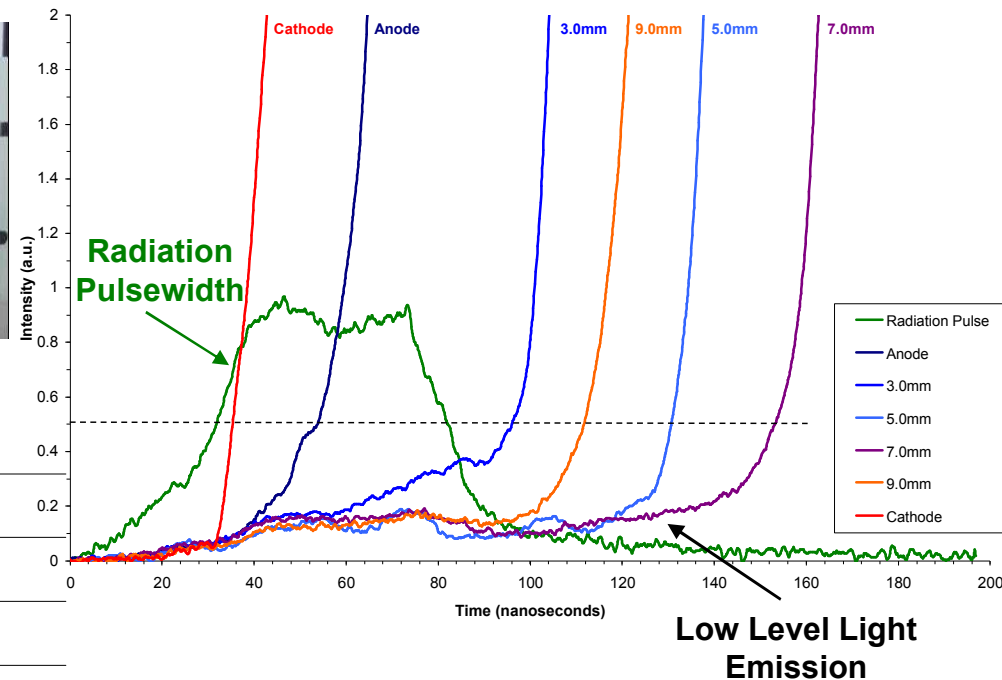
Plasma Expansion Velocity across A-K Gap:
5-10cm/ μ sec

Plasma Propagation Measurements using Silicon Avalanche Photodetectors

Anode Expansion Velocity: $4.6 \pm 0.3 \text{ cm}/\mu\text{sec}$; Cathode Expansion Velocity: $2.6 \pm 0.2 \text{ cm}/\mu\text{sec}$



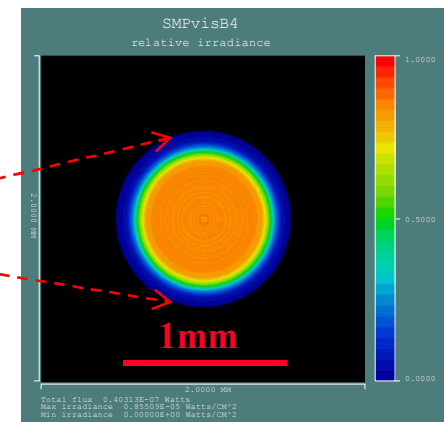
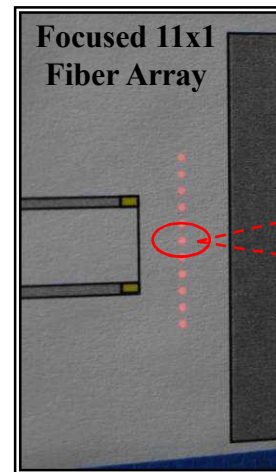
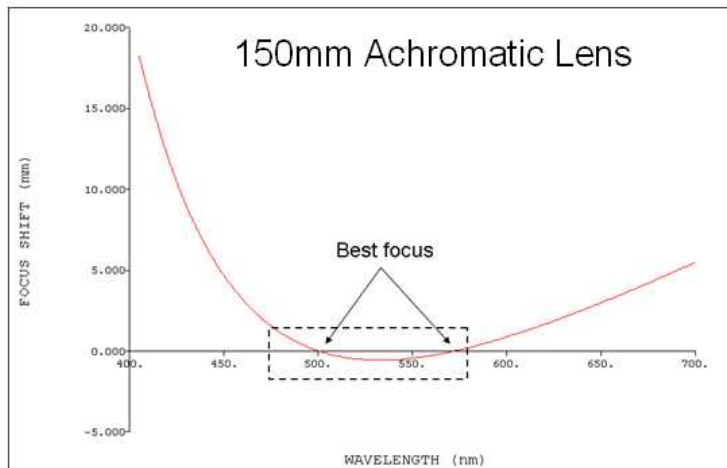
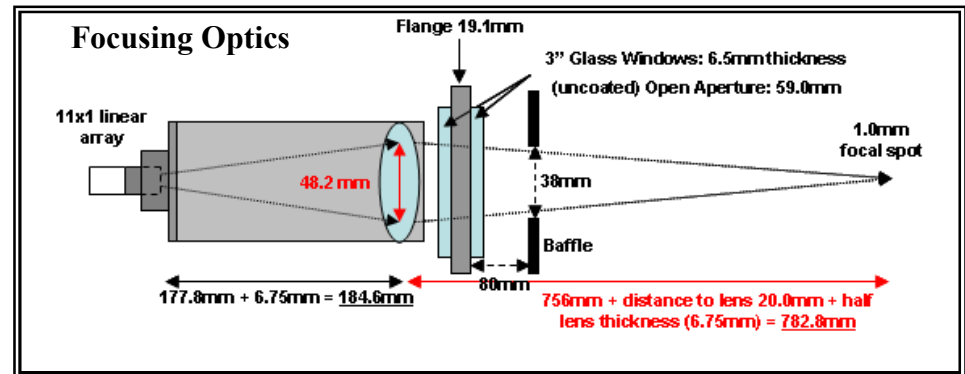
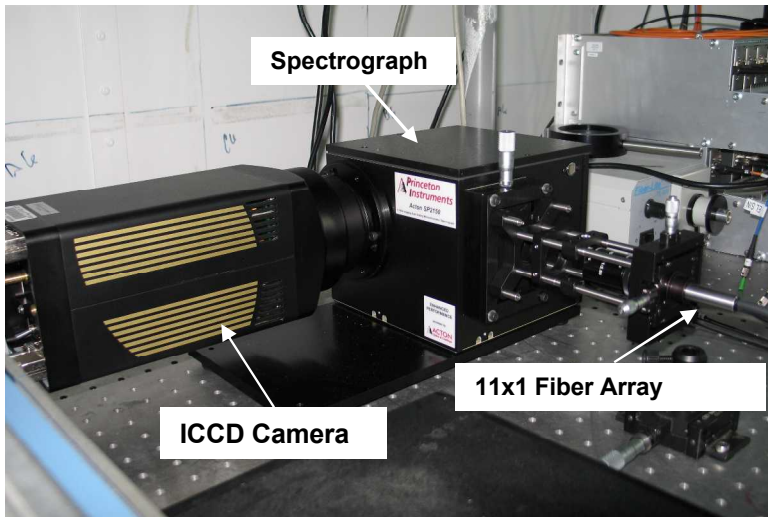
Silicon Avalanche Photodetectors



*All data taken on the same shot

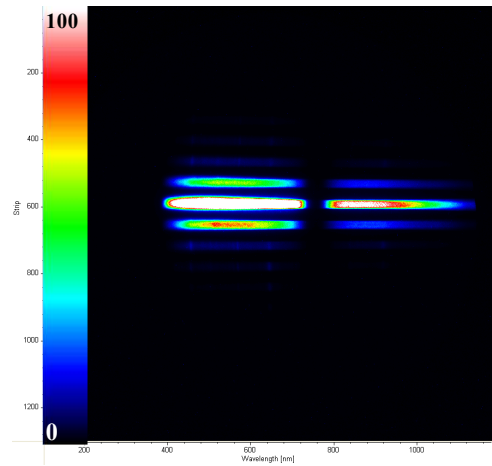
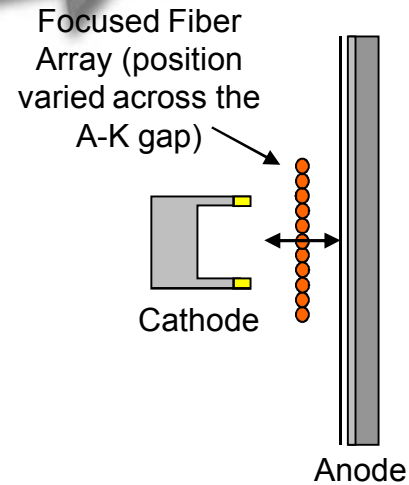
Plasma Spectroscopy Diagnostic

Spectrograph with ICCD camera

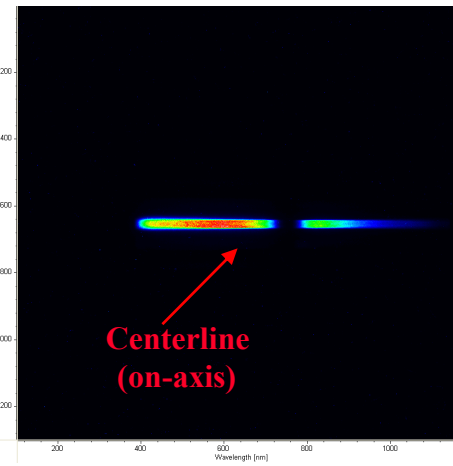


Fiber Focal Spot Size

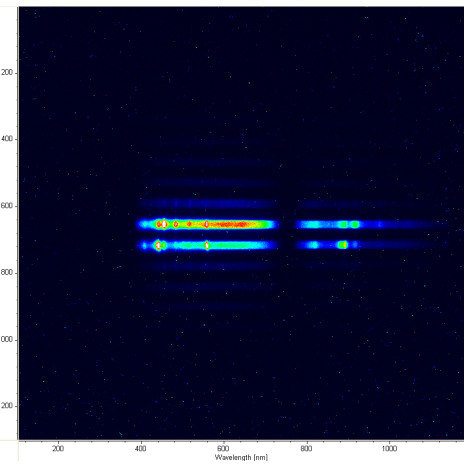
Radial Distribution of Spectra at Different Axial Locations (spectra collected on separate shots)



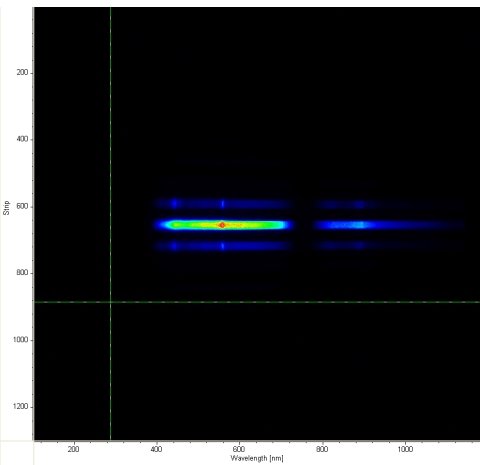
Anode



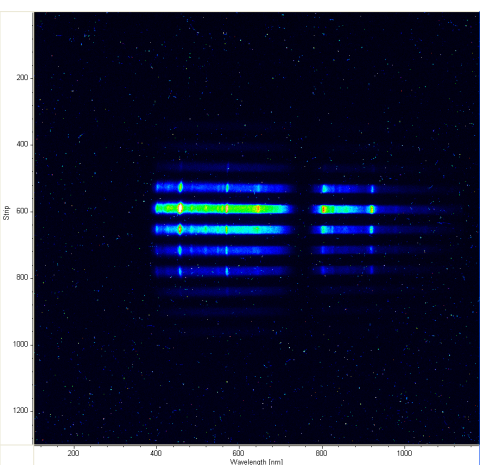
1/6 Gap



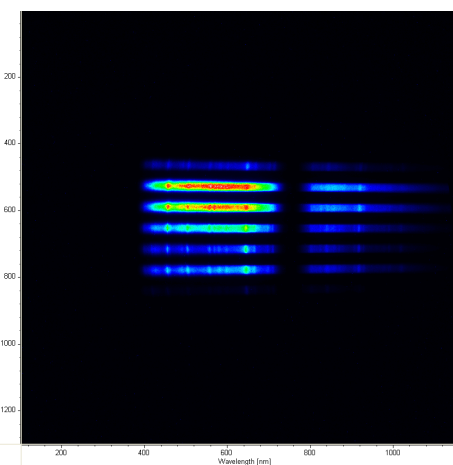
1/3 Gap



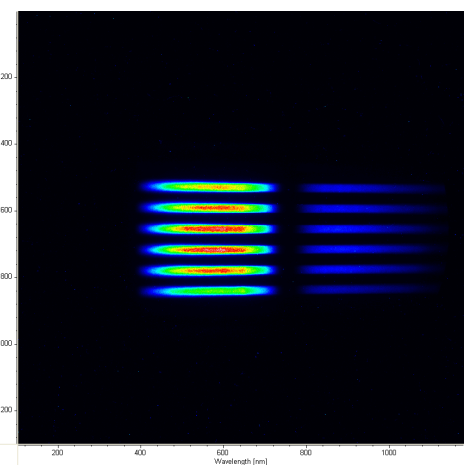
Mid-Gap



2/3 Gap



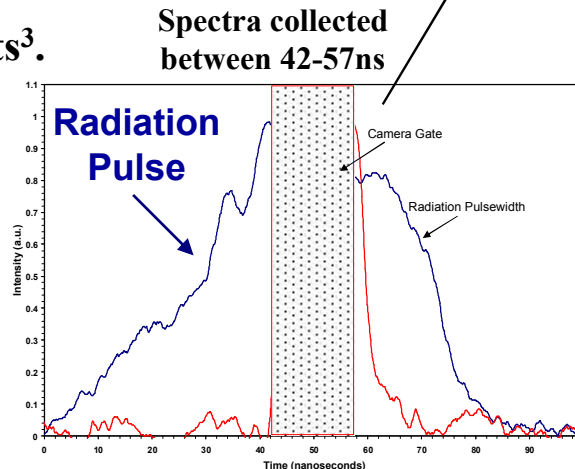
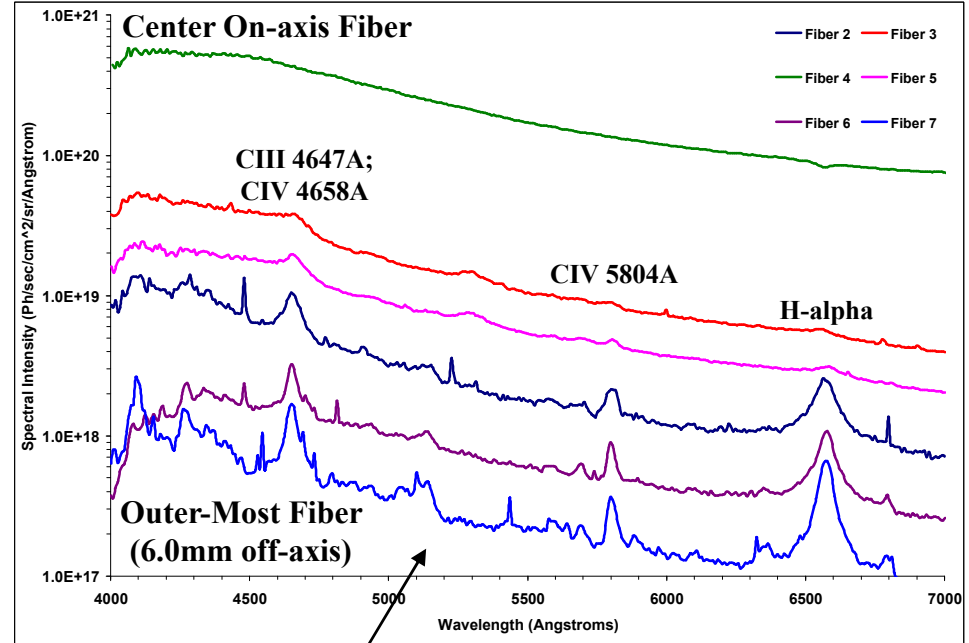
5/6 Gap



Cathode

Spectral Data at Anode Surface During the Radiation Pulse

- Spectra collected along the anode surface during the radiation pulse consist of carbon ion lines, hydrogen neutrals, and continua.
- Line of sight traverses plasmas with different properties.
- Plasma density decreases by a factor of ~35x from the center outward to 6mm.
- Asymmetries in plasma composition and density can be observed across the surface.
- Intensities calibrated in absolute units³.



Carbon Ion Lines Observed

- CIII 4647A
- CIV 4658A
- CIV 5804A

*Red box indicates when in the radiation pulse the spectra was collected.

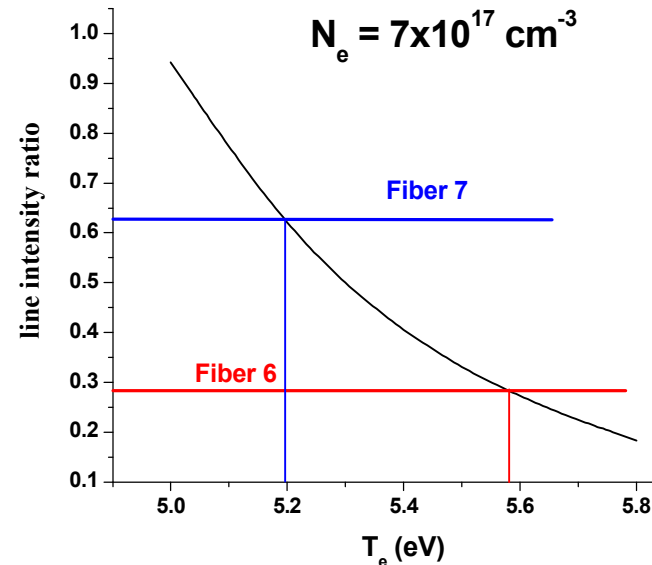
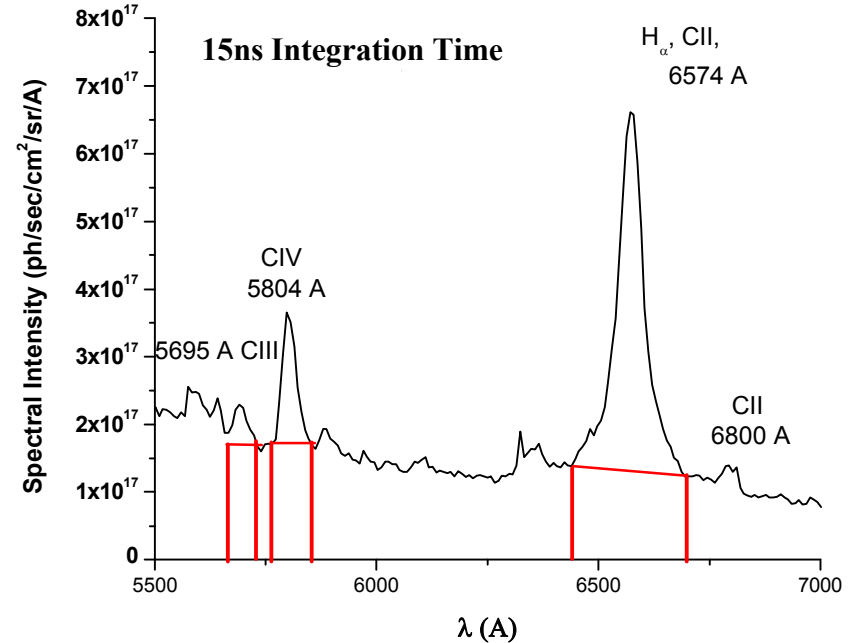
³M.D. Johnston, B.V. Oliver, D.W. Droemer, B. Frogget, et al., *Review of Sci. Instruments*, Vol. 83, No. 8, p. 083108-1.

Sample Analyses of Spectral Data off the Anode Surface Following the Radiation Pulse

Electron densities are determined from Stark Broadening of the H-alpha line and from absolute continuum intensities using collisional-radiative (CR) spectral analysis. Electron temperatures are obtained from CIII/CIV line ratios.

Fiber 7 (6.0mm off-axis on the anode surface)

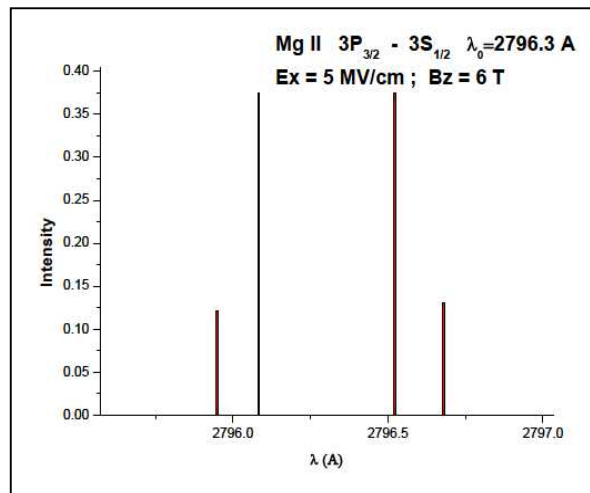
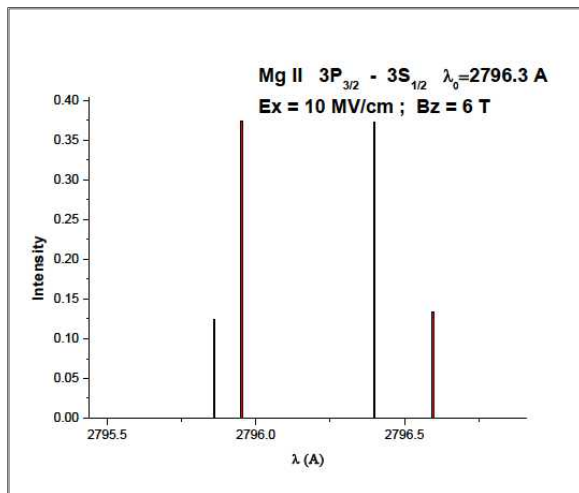
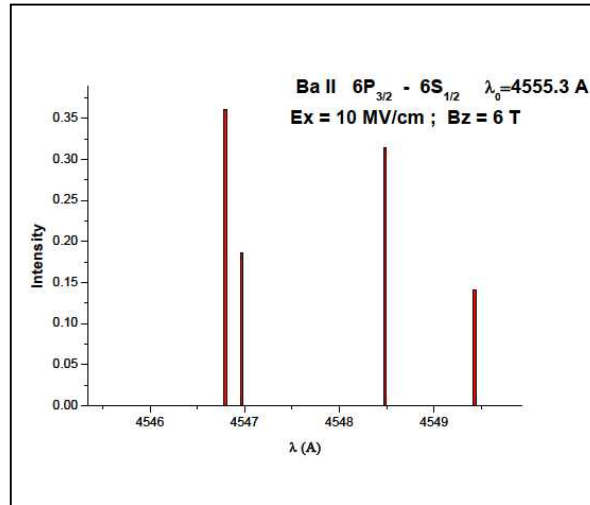
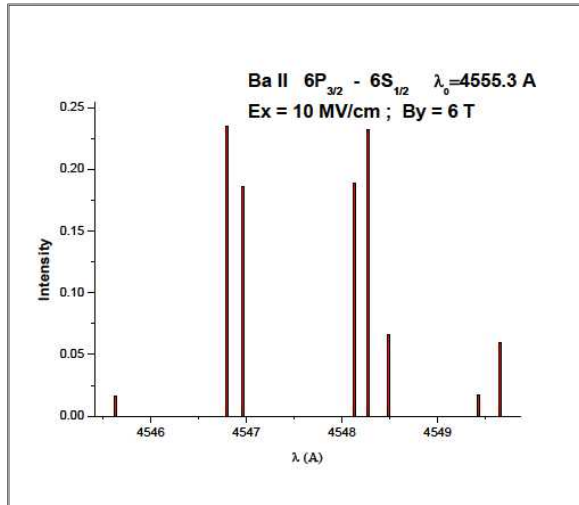
N_e from H-alpha:	$7.4 \times 10^{17} \text{ cm}^{-3}$	
N_e from Continuum:	$2.9 \times 10^{17} \text{ cm}^{-3}$	
Electron Temp. (T_e):	5.2eV	
$N_{\text{hydrogen}} (Z = 1)$:	$3.2 \times 10^{17} \text{ cm}^{-3}$	(45%)
$N_{\text{carbon}} (Z = 2.9)$:	$3.0 \times 10^{16} \text{ cm}^{-3}$	(12%)
$N_{e(\text{other})}$:	$3.0 \times 10^{17} \text{ cm}^{-3}$	(43%)



*Continuum density is averaged over the full fiber viewing area, while Stark broadening is a localized measurement.

**Analyses use the optical streak images to determine pathlengths through the plasma volumes in time.

Electric and Magnetic Field Measurements in E-Beam Diodes



- Electric and magnetic fields present in e-beam diodes fielded at RITS can be measured spectroscopy.
- Very high electric fields (MV/cm) cause shifts in the transition frequencies of spectral lines (second-order Stark effect). These shifts can be calculated and measured.
- Similarly, strong magnetic fields (several Tesla), cause splitting of spectral lines (Zeeman splitting), which can be calculated and measured.
- Through a judicious choice of transition lines and species, very large E and B fields can be measured in the vacuum gap and within the dense plasma regions.



Summary

- Dense plasmas are formed on electrode surfaces in the SMP diode during the $\sim 45\text{ns}$ FWHM radiation pulse. These plasmas migrate into the A-K gap at velocities of $5\text{-}10\text{cm}/\mu\text{sec}$.
- Spectroscopic data shows that these plasmas are composed primarily of hydrogen and carbon ion species. Electron densities of up to 10^{19} cm^{-3} have been measured on axis at the anode surface during the x-ray radiation pulse.
- It is believed that these “dense” plasma are responsible for the gradual impedance decay observed during the x-ray radiation pulse. In addition, a “rapid” impedance collapse is observed on some shots, and experiments are planned to look at this phenomena spectroscopically.
- Spectroscopic data is incorporated into LSP, a hybrid particle-in-cell / fluid dynamic code, to help design the next generation of enhanced radiographic sources.
- This type of information (density and temperature profiles in time) enhances our physics understanding of the role of plasmas in e-beam diodes.